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Alessandro Callegari, et al.

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**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
He	5,312,565	11/01	Misra, et al.			
	6,037,003	3/14/00	Gordon, et al.			
	5,728,222	3/17/98	Barbee, et al.			
	5,648,113	7/15/97	Barbee, et al.			
	5,540,777	7/30/96	Barbee, et al.			
	5,431,734	7/11/95	Chapple-Sokol, et al.			
He	4,097,314	6/27/78	Schlesier, et al.			

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

He		Eble, R., et al., "Low Temperature Aluminum Oxide Deposition Using Trimethylaluminum", <u>Journal of Electronic Materials</u> , Vol. 12, No. 3, pp. 587-601 (1983);
He		Kim, J.S., et al., "Fabrication of Aluminum Oxide Thin Films by a Low-Pressure Metalorganic Chemical Vapor Deposition Technique", <u>App. Phys. Lett.</u> , 62(7), February 15, 1993;

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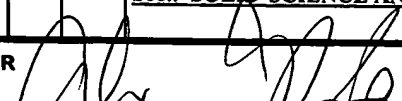
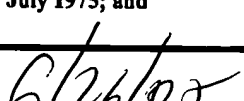
## U.S. PATENT DOCUMENTS

[illegible]

**FOREIGN PATENT DOCUMENTS**

[illegible]

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

		Lo, S.-H, et al., "Quantum-Mechanical Modelling of Electron Tunneling Current From the Inversion Layer of Ultra-Thin-Oxide nMOSFET's", <u>IEEE Electron Device Letters</u> , Vol. 18, No. 5, pp. 209-211, May 1997;
		Mutoh, H., et al., "Multilayer Metallization with Planar Interconnect Structure Utilizing CVD Al <sub>2</sub> O <sub>3</sub> Film", <u>J. Electrochem. Soc.: SOLID-SCIENCE AND TECHNOLOGY</u> , Vol. 12, No. 7, pp. 987-992, July 1975; and
EXAMINER		DATE CONSIDERED 

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